



**A dry etching system specializing in the processing of chemical compounds and non-volatile materials**

## **APX300 Dry Etcher (S Option)**

The APX300 (S option) is a dry etching system specializing in the processing of chemical compounds and non-volatile materials. It is compatible with wafers of 2 inches to 8 inches and irregular substrates, and two transport methods can be selected: "Atmospheric loading supply" and "Vacuum load lock supply" CE certificated. This equipment is a single-wafer processing type for wafers of 8 inches or smaller, and can be selected and optimized for a wide range of process applications such as power semiconductors, optical communications, high-frequency communications, RF modules, and MEMS. In addition, as a post-etching process, the ashing and rinsing chambers can be expanded according to the process application.

### **Key Features**

---

Two types of plasma sources enable high-speed and high-precision machining. Achieves high-speed deep drilling of compound materials (substrate penetration, etc.) and control of processed film thickness.

---

Achieves metal machining without residue and corrosion by adding usher and rinse chambers.

---

In-situ garment removal function with top plate enables stable machining of non-volatile materials.



## APX300 Dry Etcher ( S Option )

<https://ap.connect.panasonic.com/p/h/en/apx300-dry-etchers-option>

<b>Dimensions (mm)</b>	<p>【Load lock wafer Handling】 W 1 350 mm × D 2 230 mm × H 2 000 mm (Exclude touch panel , operation section and signal tower)</p> <p>【Atmospheric loading supply】 W 1 375 mm × D 2 600 mm × H 2 000 mm (Exclude touch panel , operation section and signal tower)</p>
<b>Plasma source</b>	ICP Plasma
<b>Model-No. (Model Name)</b>	NM-EFE3AA-S
<b>Process gas</b>	Standard 4 lines ( Maximum 6 Lines : Chlorinated Gas , Fluoride Gas , Ar , O <sub>2</sub> , He , etc. )
<b>Wafer size</b>	φ100 mm / 150 mm wafer with orientation flat φ200 mm wafer with notch <sup>*1</sup>
<b>Mass (Weight)</b>	2 000 kg (Di ers depending on machine configuration )
<b>Power Source</b>	3-phase AC 200 / 208 / 220 / 230 / 240 ±10 V , 50 / 60 Hz , 21.00 kVA <sup>*2</sup>
<b>Pneumatic Source</b>	0.5 MPa to 0.7 MPa , 250 L / min ( A.N.R. )
<b>N<sub>2</sub> Source</b>	0.1 MPa to 0.2 MPa , 50 L / min ( A.N.R. )
<b>Footnote Description</b>	<p>Please refer to the specifications on details.</p> <p>1. For other wafer sizes , please contact us.</p> <p>2. 3-phase electricity has two kinds of lineage. Figure shows total.</p>